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# Original Article Structural and Mechanical Properties of Cubic Silicon Nitride: A Molecular Dynamics Study

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**Abstract:** The molecular dynamics simulations have been used to study the microstructure as well as mechanical behavior of cubic silicon nitride  $(c-Si_3N_4)$  under the extended deformation. The silicon nitride sample was simulated under the cooling process and high pressure. At T=300 K, dominant nitrogen (N) atoms arrange into fcc lattice, and the rest of N atoms have hexagonal close-packed (hcp) and disordered structures. The hcp and disordered N atoms gather into the narrow bands. The phonon spectra of this sample are calculated and discussed. In this work we also present a molecular dynamics prediction for the elastic moduli in strained cubic silicon nitride as functions of the volumetric strain. Young's modulus and Poisson's ratio are also calculated for the c-Si<sub>3</sub>N<sub>4</sub>.

Keywords: Molecular dynamics, Si<sub>3</sub>N<sub>4</sub>, Cubic, Mechanical, Deformation.

# 1. Introduction

Silicon nitride (Si<sub>3</sub>N<sub>4</sub>) is widely used in technological applications due to its very high mechanical strength, high thermal and chemical stability, and useful semiconducting properties [1]. Beside  $\alpha$ - and  $\beta$ -Si<sub>3</sub>N<sub>4</sub> phases at the normal condition [2], third phase of Si<sub>3</sub>N<sub>4</sub> crystals has been synthesized third phase at P  $\geq$ 15 GPa and T  $\geq$  2000 K, in which Si<sub>3</sub>N<sub>4</sub> crystallizes into a cubic spinel-type structure called  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> [3]. The  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> has excellent mechanical properties with the hardness up to 43 GPa [4, 5]. By shock wave compression,  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> has been also prepared from  $\alpha$ - and  $\beta$ -Si<sub>3</sub>N<sub>4</sub>. The Si<sub>3</sub>N<sub>4</sub> powders were

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quenched upon the shock pressure of 12 to 115 GPa, in which 80% of the  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> recovered at P=54 GPa and T=2400 K with grain sizes 10-50 nm [6]. The  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> obtained to 80% percent at the shock pressure of 45 GPa and T=4000 K by using the mixtures of  $\alpha$ -Si<sub>3</sub>N<sub>4</sub> and copper powders as initial materials [7]. In fact, the  $\beta$ - $\gamma$  phase transition pressures are difficult to determine in a wide temperature range [8]. Moreover, the grain size of the  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> decreases with an increase in synthesis pressure and thus the higher pressure is favorable for eliminating pores and defects along the grain boundaries, leading to enhance the mechanical properties with improvement in the hardness [4]. Based on the optimization of the geometric structure, The first-principles calculations have shed light on why cubic (c-)  $Si_3N_4$  has the spinel structure under the high pressure and high temperature [9, 10]. The mechanical behaviors of c-Si<sub>3</sub>N<sub>4</sub> crystals have been investigated by applied the deformation. The stress-strain curves of the c-Si<sub>3</sub>N<sub>4</sub> were obtained by applied tensile and shear stress, in which the ideal tensile and shear strength were determined to be 45 and 49 GPa, respectively [11]. However, these first-principles calculations have been carried out on the perfect structure of the  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> while the experiments showed that the structure of the  $\gamma$ -Si<sub>3</sub>N<sub>4</sub> contains grain boundaries and defects [4, 12]. At the atomistic scale, molecular dynamics (MD) simulations represent a powerful complement to experimental techniques with providing mechanistic insight into experimentally observed processes [13]. Recently, the mechanical properties of  $\beta$ -Si<sub>3</sub>N<sub>4</sub> nanoporous membranes have been studied by MD simulations under the tensile deformation, suggesting that the proper introduction of the pores in nanoporous membranes leads to the transition from brittle to ductile transition in the failure mechanism [14]. Thus, in this work, we used the MD simulations to study the microstructure and mechanical behavior of the  $c-Si_3N_4$ . The  $c-Si_3N_4$  sample was obtained by the quenching process under high pressures. The microstructure of the c-Si<sub>3</sub>N<sub>4</sub> sample is characterized by the radial distribution function (RDF), fractions of SiN<sub>x</sub> structural units, bond angle distribution (BAD), common neighbor analysis (CNA), and atomic visualization. The extended deformation was applied to the c-Si<sub>3</sub>N<sub>4</sub> sample to investigate the mechanical properties of the sample.

### 2. Computational Procedures

In the MD simulation we used the two-body potential which can be found in elsewhere [15]. The pair potential is described in two terms only, including the attractive Morse-type for Si-N pair, the screened Coulomb repulsion for Si-Si and N-N pairs, and the additional dispersion term for N-N interactions. This potential has been chosen because it is computationally efficient, yields models with moderately low coordination defects and reasonable values for the enthalpy of formation [16]. The MD simulations were executed at a constant pressure (the ensemble NPT) with the Verlet algorithm and a time step of 1 fs. The periodic boundary condition was used to the simulation box. The Berendsen thermostat and barostat were applied during the simulation process to control the temperature and pressure of the systems [17].

The Si<sub>3</sub>N<sub>4</sub> sample contains 4500 Si and 6000 N atoms. The coordinates of these atoms were generated randomly in the simulation box with the size of 55 Å × 55 Å × 55 Å. The random generation ensures that the distance between neighboring atoms is always higher than 1.0 Å. This initial configuration was used as the input for the MD simulation. This Si<sub>3</sub>N<sub>4</sub> sample was heated at T = 5000 K and the P = 0 GPa for 100 ps. Then, the sample was cooled down to T = 300 K with the cooling rate of  $10^{-13}$  K/s and P = 45 GPa.

To calculate the mechanical properties, the sample was deformed by the uniform expansion of magnitude in each of the x, y and z directions. The energy – volume curve was obtained by the extending direction. The bulk modulus can be calculated as [18]:

$$B(V) = -VP'(V) = VE''(V),$$
(1)

where V is the volume of unit cell, E(V) is the corresponding energy per unit cell, and P(V) is the pressure. The second derivative E''(V) must be approximated because the calculations provide only a set of  $E(V_i)$  for a limited number of  $V_i$ . The E(V) is calculated to the form proposed by Birch [18]:

$$E(V) = E_0 + \frac{9}{8} B_0 V_0 \left[ \left( \frac{V_0}{V} \right)^{2/3} - 1 \right]^2 + \frac{9}{16} B_0 V_0 (B_0' - 4) \left[ \left( \frac{V_0}{V} \right)^{2/3} - 1 \right]^3 + \sum_{n=4}^N \gamma_n \left[ \left( \frac{V_0}{V} \right)^{2/3} - 1 \right]^n, \quad (2)$$

where  $E_0$ ,  $B_0$ ,  $V_0$  and  $B'_0$  are the equilibrium energy, volume, bulk modulus, and pressure derivative of the bulk modulus, respectively, and while N is the fitting order. Eq. (2) is a special case of the general expression:

$$E(V) = \sum_{n=0}^{N} \alpha_n V^{-2n/3} , \qquad (3)$$

where  $\alpha_n$  are the fitting parameters. This Birch fit was used to obtain the bulk modulus B and the shear modulus G. Thus, Young's modulus can be estimated as:

$$E = \frac{9BG}{(3B+G)},\tag{4}$$

and the Poisson's ratio can be calculated as:

$$\sigma = \frac{(3B - 2G)}{2(3B + G)}\tag{5}$$

## 3. Results and Discussion

The local structure of Si<sub>3</sub>N<sub>4</sub> sample has been analyzed via the pair RDFs as presented in Figue 1. The pair functions,  $\mathbf{g}_{Si-N}(r)$ ,  $\mathbf{g}_{Si-Si}(r)$  and  $\mathbf{g}_{N-N}(r)$ , show many clear and sharp peaks, indicating the ordered structure of Si<sub>3</sub>N<sub>4</sub>. The first, second and third peaks of the  $g_{Si-N}(r)$  locate at 1.83 ± 0.01, 3.24  $\pm$  0.01 and 4.17  $\pm$  0.01 Å, respectively. Based on this  $\mathbf{g}_{Si-N}(r)$ , the first minimum after the first peak is determined as  $2.23 \pm 0.01$  Å and this value is used to calculate the SiN<sub>x</sub> units. Fraction of SiN<sub>4</sub>, SiN<sub>5</sub> and SiN<sub>6</sub> units is calculated as 10.16, 8.80 and 81.04 %, respectively. Obviously, network structure of Si<sub>3</sub>N<sub>4</sub> consists of dominant SiN<sub>6</sub> units and significant SiN<sub>4</sub> and SiN<sub>5</sub> units. The first, second and third peaks of the  $\mathbf{g}_{N-N}(r)$  locate at 2.59 ± 0.01, 3.67 ± 0.01 and 4.57 ± 0.01 Å, respectively, while those of the  $\mathbf{g}_{Si-Si}(r)$  locate at 2.67 ± 0.01, 3.08 ± 0.01 and 3.70 ± 0.01 Å, respectively. Here we note that, in the  $g_{N-N}(r)$ , the distance of the second peak is approximately equal to the distance of the first peak multiplied by  $\sqrt{2}$ , indicating that the sublattice of N atoms can be arranged in the face-centered cubic (fcc) structure. To elucidate the structure of Si<sub>3</sub>N<sub>4</sub>, the CNA was used to determine the crystalline atoms [19]. Here we found that 67.35 % of N atoms arrange in the fcc structure while 5.65 % of those arrange in the face-centered cubic (hcp) structure and 27 % of those are in the disordered (d-) structure. The cross-sectional structures of Si<sub>3</sub>N<sub>4</sub> with the fcc, hcp and d- structures are showed in Figure 2. As observed in Figure 2, the fcc N atoms link together to create fcc N structure which connects to Si atoms

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which are distributed only in dominant  $SiN_6$  units and significant  $SiN_4$  units. The crystalline structure of c-Si<sub>3</sub>N<sub>4</sub> is isostructural with the mineral MgAl<sub>2</sub>O<sub>4</sub> [20] which has a fcc lattice with space group  $Fd\overline{3}m$ . The ideal spinel structure consists of a fcc sublattice of N atoms with the Si ions occupying both one eighth of the interstitial tetrahedral sites and one half of the octahedral sites [21]. Thus, this c-Si<sub>3</sub>N<sub>4</sub> is formed with the fcc N sublattice linked to significant  $SiN_4$  units and dominant  $SiN_6$  units. It is noted that the simulated distances of Si-N, Si-Si and N-N bond lengths are close to the experimental data of y-Si<sub>3</sub>N<sub>4</sub> [22] in which the distances of Si-N<sub>tet</sub>, Si-N<sub>oct</sub>, Si-Si and N-N bond lengths are 1.7849, 1.8718, 2.7343 and 2.5539 Å, respectively. Meanwhile, hcp and d- N atoms gather to form narrow bands that surround the fcc N sublattice. These hcp and d- N atoms connect to Si atoms which are distributed in  $SiN_6$ ,  $SiN_5$  and  $SiN_4$  units. We calculated the average potential energy (APE) of these fcc, hcp and d- N atoms in which the APE of fcc N atoms is -8.095 eV/atom while that of hcp and d- N atoms are -7.105 and -6.929 eV/atom, respectively. Thus, these hcp and d- N atoms are classified as the stacking faults and defects in the fcc N lattice, respectively. Furthermore, almost Si atoms from SiN<sub>5</sub> units connect to hcp and d- N atoms. These  $SiN_5$  units are considered as the most common defects [23]. We also examined the geometries of  $SiN_4$  and  $SiN_6$  units in the  $Si_3N_4$  sample. Figure 3 shows the BADs of  $SiN_4$ and  $SiN_6$  units. For both of  $SiN_4$  and  $SiN_6$  units, the peak of the BAD in fcc structure are higher and sharper than that of the BAD in hcp and d- structures, indicating that  $SiN_4$  and  $SiN_6$  units in hcp and dstructures are more distorted than those in the fcc structure. Consequently, the narrow bands including hcp and d- N structures are considered as the stacking faults and defects in the fcc N structure of c-Si<sub>3</sub>N<sub>4</sub>. The narrow bands of hcp and d- N structures are observed as the grain boundaries which are observed by STEM images [12]. This suggests that MD simulations can aid to understand more insight of structural grain boundaries at the atomic level.



Figure 1. The pair RDFs of  $Si_3N_4$  at T= 300 K.



Figure 2. Cross-sectional Si<sub>3</sub>N<sub>4</sub> sample (L<sub>x</sub> × L<sub>y</sub> × L<sub>z</sub>) at the position: a) L<sub>x</sub>/4, b) L<sub>x</sub>/2, c) 3L<sub>x</sub>/4 and d) L<sub>x</sub> (yellow color: fcc N atom, violet color: hcp N atom, red color: a- N atom, cian color: Si atom from SiN<sub>4</sub> unit, blue color: Si atom from SiN<sub>5</sub> unit and green color: Si atom from SiN<sub>6</sub> unit).

The phonon spectra  $P(\omega)$  of this c-Si<sub>3</sub>N<sub>4</sub> are calculated by using the fast Fourier transform on the velocity autocorrelation function [24]:

$$P(\omega) = \frac{1}{\sqrt{2\pi}} \int_{0}^{\infty} \left\langle \sum_{i=1}^{N} v_i(t) v_i(0) \right\rangle e^{i\omega t} d\omega, \qquad (6)$$

where  $v_i(t)$  and  $\omega$  are the velocity and angular frequency of the atom "i" at time t, respectively. The ensemble average here is substituted by time averaging, which is performed over 30 ps after the realization of the equilibrium state. Figure 4 shows the calculated partial and total phonon density of states (PDOS) of c-Si<sub>3</sub>N<sub>4</sub> sample. The total PDOS spans up to about 1145 cm<sup>-1</sup>, which is about 2.3% and 10% greater than the maximum frequencies (1119 and 1030 cm<sup>-1</sup>) obtained by Marian et al. [15] and by Fang et al. [21], respectively. We note that the  $\gamma$ -Si<sub>3</sub>N<sub>4</sub>, obtained by ab initio simulations [21], does not

consist of  $SiN_5$  units in the network structure. Different vibration contributions from three different Si atoms are recognizable as presented in Figure 4. The low energy vibrations (<550 cm<sup>-1</sup>) originate mainly from Si atoms. The N atoms are involved in the vibrational modes over the high energy range (>670 cm<sup>-1</sup>).

In applying the MD simulations to the moduli calculation, the sample was extended uniformly in the x, y and z directions at T = 300 K in NPT ensemble. The energy and volume of the system were determined at the same time. The energy-volume curve is showed in Figure 5. Based on this curve, the system energy as a function of the volume (V<sup>-2/3</sup>) can be estimated by a function using the equation (3) with the following coefficients obtained through curve fitting:

$$\alpha_{0} = -83$$

$$\alpha_{1} = 4786$$

$$\alpha_{2} = -103950$$

$$\alpha_{3} = 1000910$$

$$\alpha_{4} = -3605650$$
(7)



Figure 3. The bond angle distribution in: a) SiN<sub>4</sub> units and b) SiN<sub>6</sub> units.



Figure 4. Partial and total PDOS for c-Si<sub>3</sub>N<sub>4</sub> calculated from this MD simulations.

Now, we used these coefficients in Eq. (7) to calculate the bulk modulus in Eq. (1), B=308 GPa and this value is good agreement with experimental data [5, 12] and other calculations [11].

For a cubic crystal, the elastic moduli can be divided into two classes, the bulk modulus  $B=(C_{11}+2C_{12})/3$ , and the two shear moduli,  $C_{11}-C_{12}$  and  $C_{44}$  [25]. The shear moduli can be estimated the derivative of the energy as a function of a lattice strain [26]. The total energy can be expressed in powers of the strain [25],

$$E(\delta) = E(-\delta) = E(0) + (C_{11} - C_{12})V_0\delta^2 + O[\delta^4], \qquad (8)$$

and

$$E(\delta) = E(-\delta) = E(0) + \frac{1}{2}C_{44}V_0\delta^2 + O[\delta^4], \qquad (9)$$

where E(0) is the energy of unstrained lattice at the volume  $V_0$ , and the dilation  $\delta$  is given by,

$$\delta = \frac{V - V_0}{V_0}.\tag{10}$$

As observed in Figure 2, since the c-Si<sub>3</sub>N<sub>4</sub> sample is not true isotropic materials, bound on G can be determined by Hashin and Shtrikman [27],

$$G_{1} = G_{1}^{*} + \frac{3(G_{2}^{*} - G_{1}^{*})}{5 - 4\beta_{1}(G_{2}^{*} - G_{1}^{*})}, \qquad (11)$$

and

$$G_2 = G_2^* + \frac{2(G_1^* - G_2^*)}{5 - 6\beta_2(G_1^* - G_2^*)},$$
(12)

where

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$$G_1^* = \frac{(C_{11} - C_{12})}{2}, \ G_2^* = C_{44}$$
 (13)

and

$$\beta_1 = -\frac{3(B+2G_1^*)}{5G_1^*(3B+4G_1^*)}, \ \beta_2 = -\frac{3(B+2G_2^*)}{5G_2^*(3B+4G_2^*)}$$
(14)

The Hashin bound  $G_H$  is designated as the larger of  $G_1$  and  $G_2$ , while the Shtrikman bound  $G_S$  is the smaller. Thus, G can be calculated as,

$$G = \frac{G_H + G_S}{2} \tag{15}$$

From the c-Si<sub>3</sub>N<sub>4</sub> sample, G is estimated as 186 GPa. In the experiments, the value of the G is determined as 148 GPa [5] and 247.5 GPa [12] because of the anisotropy of this c-Si<sub>3</sub>N<sub>4</sub> sample. Thus, the value of 186 GPa from our calculations is reasonable. Here the value of Young's modulus is determined as 464 GPa and the value of Poisson's ratio is estimated as 0.248. We note that the size effect of sample on the microstructure and mechanical property is not investigated in this work.



Figure 5. The total energy versus the volume system at T=300 K.

#### 4. Conclusion

c-Si<sub>3</sub>N<sub>4</sub> sample was simulated by the MD simulations under the cooling process and high pressure of 45 GPa. The c-Si<sub>3</sub>N<sub>4</sub> contains dominant fcc N atoms linked to the Si atoms which are distributed in both significant SiN<sub>4</sub> and dominant SiN<sub>6</sub> units. The hcp and d- N atoms gather into the band, in which Si atoms are distributed in dominant SiN<sub>6</sub> units, significant SiN<sub>5</sub>, and significant SiN<sub>4</sub> units. The bands of hcp and d- N atoms are considered such as the grain boundaries in the c-Si<sub>3</sub>N<sub>4</sub>. The PDOS has a cutoff energy of 1145 cm<sup>-1</sup> with the contributions from N atoms in the high energy range (550 – 1145 cm<sup>-1</sup>), while the contributions from Si atoms are predominantly over the lower energy range. The extended

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deformation was carried out on the  $c-Si_3N_4$  sample. The MD-simulated value of bulk modulus well consists with those measured experimentally and calculated from the first-principles calculations. The value of the shear modulus, G=186 GPa, is reasonable due to the anisotropy of the c-Si<sub>3</sub>N<sub>4</sub>. Young's modulus and Poisson's are also determined based on these bulk and shear moduli.

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